

Notice of References Cited

Application/Control No.

09/916,381

Applicant(s)/Patent Under
Reexamination
HAGA ET AL.

Examiner

Lynette T. Umez-Eronini

Art Unit

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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6284721-B1	09-2001	Lee	510/175
	B	US-6623856-B1	09-2003	Kodas et al.	428/402
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	JP-11-194120	07-1999	Japan	Satoro et al.	G01N 31/12
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Satoro et al., "Method and Apparatus for Quantitative Analysis of Mixed Acid Solution in Etching Process as Well as Etching Control Method and Preparation of the Mixed Acid Solution, July 21, 1999, English Abstract of JP 11-194120, 1 page.
	V	Satoro et al., "Method and Apparatus for Quantitative Analysis of Mixed Acid Solution in Etching Process as Well as Etching Control Method and Preparation of the Mixed Acid Solution, July 21, 1999, English-Computer translation of JP 11-194120, 7 pages.
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.